

TEM Holder Cleaning & Storage System

TSP-100

For cleaning and storage of TEM sample holders

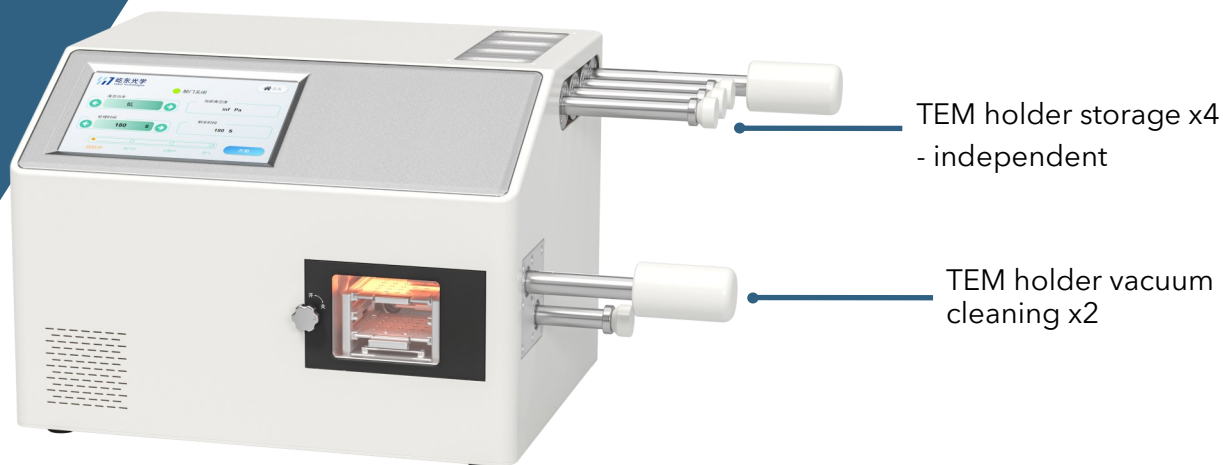


Advantages:

- Combines TEM sample-holder cleaning and vacuum storage within a single system.
- Compatible with most commonly used TEM sample holders.
- Equipped with two cleaning ports and four dedicated storage ports.

CLEANING MODE

- Uses inductively coupled plasma (ICP) technology to generate a significantly higher plasma density than traditional capacitively coupled plasma systems.
- Produces a high concentration of reactive oxygen species to efficiently remove hydrocarbon contaminants from sample surfaces.
- Rapidly heats the sample chamber to temperatures of up to 150°C.
- The downstream plasma cleaning process minimises direct ion bombardment, protecting delicate samples and preserving their original surface morphology.



SPECIFICATIONS

TSP-100 Specifications			
Overall Dimensions		500 x 540 x 400mm	
Dimensions of Chamber		120 x 120 x 120mm	
Touch Screen Size		10 inches	
Cleaning Power		0-100W (adjustable)	
Weight		50kg	
Power Supply		220V; 50/60Hz	
Dry Pump		≥ 3m ³ /h pumping speed	
Humidity		≤ 60%	
Cleaning Chamber		Storage Chamber	
Cleaning ports	2	Storage ports	4
Gas type	Ar, O ₂ , H ₂ and other mixed gases	Gas type	Inert gases such as N ₂ , Ar
Temperature range	Equipped with heating lamp, max temp. 150°C	Air tightness	200 Pa to 5000 Pa
Compatibility	TFS and JEOL TEM holders	Vacuum	100–5000 Pa
Working pressure	≤ 80Pa (with sample loaded)		
TEM grid	Ø3 mm standard TEM grids		